

Viacheslav Kazmiruk graduated from Moscow State Technical University named after N.E. Bauman and since 1975 to 1984 he was working in Institute of Solid State Physics as engineer and lead engineer for development of attachments to both transmission and scanning electron microscope.

Since 1984 to present time he is working in Institute of Microelectronics Technology (IMT), Russian Academy of Sciences (RAS). Since 1988 to present time he is a head of the laboratory of scanning electron microscopy.

Since 1983 to 1990 he was a head of joint Department of IMT and Scientific Instrument Factory of RAS, responsible for mini SEM 100 design and manufacturing.

He is Member of Bureau of Russian Scientific Council on Electron Microscopy and Chief Designer of SEMs and e-beam Lithography System in Russian Federation.

Subject of his scientific research is including a study of a signal formation in a SEM, design of electron optics for SEMs and e-beam lithography systems, development a technology for micro electron optics. He has several awards for design of SEM MicroScan MS20 achieved at Russian and International Salon of Inventions.